

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 05542-146009	Application No. Unassigned
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary)		Applicant Manoocher Birang et al	
		Filing Date Herewith	Group Art Unit Unassigned
(37 CFR §1.98(b))			

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication/ Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
SLM	AA	4,272,924	06/16/81	Masuko, et al.			
	AB	4,328,068	05/04/82	Curtis			
	AC	4,512,847	04/23/85	Brunsch, et al.			
	AD	4,793,895	12/27/88	Kaanta et al.			
	AE	4,948,259	08/14/90	Enke et al.			
	AF	4,954,142	09/04/90	Carr, et al.			
	AG	5,036,015	07/1991	Sandhu et al.			
	AH	5,081,421	01/14/92	Miller, et al.			
	AI	5,097,430	03/17/92	Birang			
	AJ	5,132,617	07/21/92	Leach, et al.			
	AK	5,196,353	03/23/93	Sandhu, et al.			
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	AM	5,219,787	06/15/93	Carey et al.			
	AN	5,234,868	08/10/93	Cote			
	AO	5,240,552	08/31/93	Yu et al.			
	AP	5,242,524	09/07/93	Leach et al.			
	AQ	5,257,478	11/02/93	Hyde et al.			
	AR	5,265,378	11/30/93	Rostoker			
	AS	5,294,289	03/15/94	Heinz et al.			
	AT	5,308,438	05/03/94	Cote et al.			
	AU	5,321,304	06/14/94	Rostoker			
	AV	5,332,467	07/26/94	Sune et al.			
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SLM	AAA	5,489,233	02/1996	Cook et al.			

Examiner Signature <i>Shantese A. Morales</i>	Date Considered 5/14/04
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U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication/ Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
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	BB	5,609,511	03/11/97	Moriyama, et al.			
	BC	5,672,091	09/30/97	Takahashi et al.			
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	BG	6,146,248	11/2000	Jairath et al.			
SLM	BH	US-2001/0036805	05/2001	Birang et al.			

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
SLM	BI	CA 625,573	08/15/61	Canada Patent				
	BJ	EP 0 738 561 A1	10/1996	Europe				
	BK	EP 468 897	01/29/92	Europe				
	BL	EP-A-0 352 740	01/90	Europe				
	BM	EP-A-0 633 265	07/19/95	Europe				
	BN	FR-A-1 075 634	10/54	France				
	BO	JP 2-222533	09/05/90	Japan Abstract				
	BP	JP 259938	06/10/89	Japan Abstract				
	BQ	JP 3-234467	10/18/91	Japanese Patent Application				
	BR	JP 5-138531	06/01/93	Japan Abstract				
	BS	JP 5-309558	02/1993	Japan				
	BT	JP 58-4353	01/11/83	Japan				
	BU	JP 59-74635	04/27/84	Japan Abstract				
	BV	JP 61-164773	07/25/86	Japan Abstract				
SLM	BW	JP 62-190728	08/20/87	Japan Abstract				

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Foreign Patent Documents or Published Foreign Patent Applications								
Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
SLM	CA	JP 62-211927	09/07/87	Japan Abstract				
	CB	JP 62-283678	09/12/87	Japan Abstract				
	CC	JP 63-256344	10/24/88	Japan Abstract				
	CD	JP 7-052032	02/1995	Japan				
SLM	CE	WO 93/20976	10/1993	WIPO				

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
SLM	CF	Hench, "In situ real-time ellipsometry for film thickness measurement and control," J. Vac. Sci. Technol. A. Vol. 10, No. 4:934-938 (Jul/Aug. 1992).
	CG	Sautter, et al., "Development Process Control and Optimization Utilizing an End Point Monitor," SPIE Vol. 1087:312-321 (1989).
	CH	Jurczyk, et al., "Process Detection System," IBM Technical Disclosure Bulletin, Vol. 18 No. 6:1867-1870 (November 1975).
	CI	Anonymous, "End-Point Detection of Oxide Polishing and Planarization of Semiconductor Devices," Research Disclosure, No. 340 (August 1992).
	CJ	Rodel, "Wafer Mounting Assemblies and Materials", ©1992 Rodel, Scottsdale, Arizona.
	CK	Carotta, et al., "Effect of Thickness and Surface Treatment on Silicon Water Reflectance," Solar Energy Materials and Solar Cells 27: 265-272 (1992).
SLM	CL	Rodel, "Glass Polishing Pads", January 1993, Scottsdale, Arizona

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